



03500.015262

*QP-1762*  
*JFW*  
PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: )  
: Examiner: M. Padgett  
TAKESHI SHISHIDO ET AL. )  
: Group Art Unit: 1762  
Application No.: 09/822,191 )  
:  
Filed: April 2, 2001 )  
:  
For: EXHAUST PROCESSING METHOD, )  
PLASMA PROCESSING METHOD :  
AND PLASMA PROCESSING )  
APPARATUS : August 25, 2004

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

AMENDMENT

Sir:

a) Introductory Comments

In response to the Office Action date May 25, 2004, kindly amend the  
subject application as follows.

I hereby certify that this correspondence is being deposited with the  
United States Postal Service as first-class mail in an envelope addressed  
to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-  
1450 on

August 25, 2004

(Date of Deposit)

Jason M. Okun

(Name of Attorney for Applicants)

Signature

August 25, 2004

Date of Signature